

Discussion/action points

Nr.	Description	Responsible
1.	AI-MQW Design Simulation results on single QW shown. Design space mapping to follow	Weiming
2.	Planning of tasks with Nanolab CW 44 will yield a detailed plan.	Weiming
3	ICP etch update from SMART Rui gives his views on recent experiments with CH ₄ -H ₂ recipe on SMART's ICP. There is difference in side wall angle and roughness between 40 cycle ICP and 2 times 20 cycle ICP etch.	Rui
4	BCB update 2 nd experiment ongoing with BCB on SiO ₂ /InP wafer. Metal definition has been performed. Tape-test is following	Tjibbe

Next meeting is 30th October, 2017, 13:30

